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Roll No.							Total No. of Pages: 0	2

Total No. of Questions: 18

B.Tech. (ECE) (Sem.-5) VLSI/ULSI TECHNOLOGY Subject Code: BTEC-905C-18 M.Code: 78709

Time: 3 Hrs. Max. Marks: 60

INSTRUCTIONS TO CANDIDATES:

- SECTION-A is COMPULSORY consisting of TEN questions carrying TWO marks each.
- SECTION-B contains FIVE questions carrying FIVE marks each and students have to attempt any FOUR questions.
- SECTION-C contains THREE questions carrying TEN marks each and students have to attempt any TWO questions.

SECTION-A

Write briefly:

- 1) Define polishing process.
- Explain dry, HCL dry and wet oxidation.

 Define the term lithograph. 2)
- 3)
- 4)
- What are various clean room and safety requirements? 5)
- What are the desired properties of metallization for integrated circuits? 6)
- Explain mask generation. 7)
- 8) Enlist RTP techniques.
- 9) Define rapid thermal processing.
- 10) Explain CVD.

1 | M - 78709 (S2) - 357



SECTION-B

- 11) Describe characterization of impurity profiles.
- 12) Explain the various effects of impurities and damage on oxidation rate.
- 13) What are wet chemical etching techniques?
- 14) Explain RIE techniques.
- 15) Explain newer lithography techniques for VLSI/ULSI.

SECTION-C

- 16) Explain CVD techniques for deposition of polysilicon.
- 17) Describe various oxidation techniques.
- 18) List possible ways of growing an oxide on a substrate without forming oxidation induced stacking faults.

NOTE: Disclosure of Identity by writing Mobile No. or Making of passing request on any page of Answer Sheet will lead to UMC against the Student.

2 | M - 78709 (S2) - 357